

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF:  
Imran Hashim, et al.

SERIAL NO.: 09/138,429

FILED: August 24, 1998

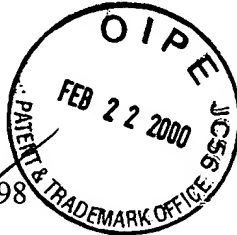
FOR: Collimated and Long Throw Magnetron  
Sputtering of Nickel/Iron Films for  
Magnetic Recording Head Applications

GROUP ART UNIT: 1753

EXAMINER: Julian A. Mercado

Assistant Commissioner of Patents  
Washington, D.C. 20231

Sir:



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37 C.F.R. 1.8

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**RESPONSE TO OFFICE ACTION DATED NOVEMBER 12, 1999**

In response to the Office Action dated November 12, 1999, having a shortened statutory period for response set to expire on February 12, 2000, please enter the following amendment:

## IN THE SPECIFICATION

On page 2, line 29, please replace “through” with --throw--.

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## IN THE CLAIMS

1. (Amended) An apparatus for depositing a magnetic film, comprising:  
a sputtering chamber containing a target, a substrate support having a surface that is separated from the target, and a grounded collimator positioned between the target and the substrate support; and  
a magnet array disposed within the chamber to form a substantially parallel magnetic field at the surface of the substrate support.
2. (Amended) The apparatus of claim [2] 1, wherein the target comprises a material that retains magnetic properties when deposited on the surface of [the] a substrate.